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PPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO
10/808,354	03/25/2004	Takaaki Tanaka	111988.01	5452
25944 759	90 05/04/2005		EXAMINER	
OLIFF & BERRIDGE, PLC			TON, MINH TOAN T	
P.O. BOX 19928 ALEXANDRIA, VA 22320			ART UNIT	PAPER NUMBER
			2871	
			DATE MAILED: 05/04/2001	DATE MAILED: 05/04/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)				
	10/808,354	TANAKA ET AL.				
Office Action Summary	Examiner	Art Unit				
,	Toan Ton	2871				
The MAILING DATE of this communication app Period for Reply	pears on the cover sheet with the	correspondence address				
A SHORTENED STATUTORY PERIOD FOR REPL THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.1 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a repl If NO period for reply is specified above, the maximum statutory period Failure to reply within the set or extended period for reply will, by statute Any reply received by the Office later than three months after the mailin earned patent term adjustment. See 37 CFR 1.704(b).	136(a). In no event, however, may a reply be by within the statutory minimum of thirty (30) d will apply and will expire SIX (6) MONTHS fro e, cause the application to become ABANDON	timely filed ays will be considered timely. m the mailing date of this communication. IED (35 U.S.C. § 133).				
Status						
1) Responsive to communication(s) filed on	·					
2a) ☐ This action is FINAL . 2b) ☑ This	s action is non-final.					
,	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.					
Disposition of Claims						
 4) ☐ Claim(s) 1-6 is/are pending in the application. 4a) Of the above claim(s) is/are withdra 5) ☐ Claim(s) is/are allowed. 6) ☐ Claim(s) 1-6 is/are rejected. 7) ☐ Claim(s) is/are objected to. 8) ☐ Claim(s) are subject to restriction and/or 						
Application Papers						
9) The specification is objected to by the Examiner.						
10)☐ The drawing(s) filed on is/are: a)☐ accepted or b)☐ objected to by the Examiner.						
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).						
Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the Ex	,					
Priority under 35 U.S.C. § 119						
a) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of: 1. Certified copies of the priority document 2. Certified copies of the priority document 3. Copies of the certified copies of the priority application from the International Burear * See the attached detailed Office action for a list	is have been received. is have been received in Applica rity documents have been receiv u (PCT Rule 17.2(a)).	ntion No. <u>1/076312</u> . ved in this National Stage				
Attachment(s)						
1) Notice of References Cited (PTO-892)	ry (PTO-413)					
 Notice of Draftsperson's Patent Drawing Review (PTO-948) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date 	Paper No(s)/Mail 5) Notice of Informal 6) Other:	Date Patent Application (PTO-152)				

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Art Unit: 2871

Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 2. Claims 1-2, 4 and 6 are rejected under 35 U.S.C. 102(b) as being anticipated by Shigeta et al (US 5268781).

Shigeta discloses a manufacturing method for a substrate for a liquid crystal display device by oblique evaporation of an inorganic material on an underlayer having a gap section on the surface formed on the substrate so as to form the inorganic alignment layers, comprising the steps of (see at least Figure 2, Example 1): a first oblique evaporation step by unidirectional oblique evaporation of the inorganic material on the substrate on which the underlayer having the gap section is formed on the surface of the substrate so as to form the first inorganic oblique evaporation layer; a second oblique evaporation step by oblique evaporation of the inorganic material from at least a different azimuth angle inside the substrate from the oblique evaporation direction of the inorganic material in the first oblique evaporation step so as to form the second oblique evaporation layer in an area close to the gap section and on the first inorganic oblique evaporation layer.

Shigeta discloses a difference in angles formed between the two directions/steps of 90 degrees (see at least col. 8, lines 55-56).

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Shigeta discloses material for the alignment layer comprising inorganic material such as silicon oxide.

Claim Rejections - 35 USC § 103

- 3. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 4. Claims 1 and 3-6 are rejected under 35 U.S.C. 103(a) as being unpatentable over Johnson (GB 1 583 176, IDS).

Johnson discloses a manufacturing method for a substrate for a liquid crystal display device by oblique evaporation of an inorganic material on an underlayer having a gap section on the surface formed on the substrate so as to form the inorganic alignment layers, comprising the steps of (see at least Figures 2-3): a first oblique evaporation step by unidirectional oblique evaporation of the inorganic material on the substrate on which the underlayer having the gap section is formed on the surface of the substrate so as to form the first inorganic oblique evaporation layer; a second oblique evaporation step by oblique evaporation of the inorganic material from at least a different azimuth angle inside the substrate from the oblique evaporation direction of the inorganic material in the first oblique evaporation step so as to form the second oblique evaporation layer in an area close to the gap section and on the first inorganic oblique evaporation layer.

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Johnson discloses the LCD device having a deposition angle in the first oblique evaporation step of less than 15° (overlapping Applicant's claimed range of 5-10) and a deposition angle in the second oblique evaporation step of 20°-45° (overlapping Applicant's claimed range of 25-30), wherein the device yields advantages such as improved contrast. Therefore, it would have been obvious to one of ordinary skill in the art to employ a deposition angle in the first oblique evaporation step of less than 15° (overlapping Applicant's claimed range of 5-10) and a deposition angle in the second oblique evaporation step of 20°-45° (overlapping Applicant's claimed range of 25-30) for advantages such as improved contrast. Further, overlapping ranges have been held as at least obvious.

Johnson discloses the thickness of the first inorganic layer of 6 nm (within Applicant's claimed range of 5-16 nm) and the thickness of the second inorganic layer of 25 nm (within Applicant's claimed range of 10-40 nm).

Johnson discloses materials for the alignment layer comprising inorganic material such as silicon oxide.

Conclusion

5. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure.

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Contact Information

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Toan Ton whose telephone number is (571) 272-2303.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

April 25, 2005

'TÖANTON PRIMARY EXAMINER